

## CLAIMS

1. A microfluidic device, comprising  
a substrate;  
5 a plurality of resin layers formed on the substrate; and  
a three-dimensional fluid circuit formed in the plurality of the resin layers.
2. A method of manufacturing a microfluidic device, comprising the steps of:  
(a) forming a resin layer on a substrate, and forming a groove having a  
10 predetermined pattern which functions as a fluid flow path by removing the resin  
layer by laser processing;  
(b) forming a subsequent resin layer by coating a resin on the overall  
surface of the resin layer having been processed, and forming a groove and/or a  
throughhole to the groove formed in the resin layer coated with the resin, by laser  
15 processing of the subsequent resin layer;  
(c) repeating the step (b); and  
(d) forming a three-dimensional fluid circuit by finally forming inlets and  
an outlet by resin coating.
- 20 3. The method of manufacturing the microfluidic device according to Claim 2,  
wherein the resin is formed by a lamination method.
4. The method of manufacturing the microfluidic device according to Claim 2,  
wherein the resin layer is formed by a spin coat method.